

Han Haitjema

List of Publications by Year in descending order

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85
papers

3,219
citations

236833

25
h-index

155592

55
g-index

85
all docs

85
docs citations

85
times ranked

1690
citing authors

#	ARTICLE	IF	CITATIONS
1	Geometric error measurement and compensation of machines—An update. CIRP Annals - Manufacturing Technology, 2008, 57, 660-675.	1.7	757
2	Measurement technologies for precision positioning. CIRP Annals - Manufacturing Technology, 2015, 64, 773-796.	1.7	397
3	Dimensional Micro and Nano Metrology. CIRP Annals - Manufacturing Technology, 2006, 55, 721-743.	1.7	273
4	On-machine and in-process surface metrology for precision manufacturing. CIRP Annals - Manufacturing Technology, 2019, 68, 843-866.	1.7	259
5	Modeling and verifying non-linearities in heterodyne displacement interferometry. Precision Engineering, 2002, 26, 448-455.	1.8	113
6	Calibration and verification of areal surface texture measuring instruments. CIRP Annals - Manufacturing Technology, 2015, 64, 797-813.	1.7	96
7	Bio-inspired textures for functional applications. CIRP Annals - Manufacturing Technology, 2018, 67, 627-650.	1.7	88
8	Bandwidth characteristics and comparisons of surface texture measuring instruments. Measurement Science and Technology, 2010, 21, 032001.	1.4	82
9	Development of a Silicon-based Nanoprobe System for 3-D Measurements. CIRP Annals - Manufacturing Technology, 2001, 50, 365-368.	1.7	75
10	Deformation and wear of pyramidal, silicon-nitride AFM tips scanning micrometre-size features in contact mode. Measurement: Journal of the International Measurement Confederation, 1999, 25, 203-211.	2.5	61
11	The optical, electrical and structural properties of fluorine-doped, pyrolytically sprayed titanium dioxide coatings. Solar Energy Materials and Solar Cells, 1989, 18, 283-297.	0.4	57
12	Uncertainty in measurement of surface topography. Surface Topography: Metrology and Properties, 2015, 3, 035004.	0.9	49
13	Calibration of displacement sensors up to 300 Åm with nanometre accuracy and direct traceability to a primary standard of length. Metrologia, 2000, 37, 25-33.	0.6	46
14	Noise bias removal in profile measurements. Measurement: Journal of the International Measurement Confederation, 2005, 38, 21-29.	2.5	40
15	Metrological characteristics for the calibration of surface topography measuring instruments: a review. Measurement Science and Technology, 2021, 32, 032001.	1.4	39
16	Dynamic probe calibration in the 1/4m region with nanometric accuracy. Precision Engineering, 1996, 19, 98-104.	1.8	37
17	International comparison of roundness profiles with nanometric accuracy. Metrologia, 1996, 33, 67-73.	0.6	37
18	Uncertainty analysis of roughness standard calibration using stylus instruments. Precision Engineering, 1998, 22, 110-119.	1.8	34

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19	Physical properties of pyrolytically sprayed tin-doped indium oxide coatings. <i>Thin Solid Films</i> , 1991, 205, 93-100.	0.8	33
20	Design and calibration of a parallel-moving displacement generator for nano-metrology. <i>Measurement Science and Technology</i> , 1998, 9, 1098-1104.	1.4	32
21	Electrical properties of sprayed tin oxide layers. <i>Thin Solid Films</i> , 1989, 177, 17-33.	0.8	31
22	Role of surfaces and interfaces in solar cell manufacturing. <i>CIRP Annals - Manufacturing Technology</i> , 2014, 63, 797-819.	1.7	28
23	A silicon-etched probe for 3-D coordinate measurements with an uncertainty below 0.1 μm . <i>IEEE Transactions on Instrumentation and Measurement</i> , 2001, 50, 1519-1523.	2.4	27
24	An international comparison of surface texture parameters quantification on polymer artefacts using optical instruments. <i>CIRP Annals - Manufacturing Technology</i> , 2016, 65, 529-532.	1.7	27
25	The physical properties of fluorine-doped tin dioxide films and the influence of ageing and impurity effects. <i>Solar Energy Materials and Solar Cells</i> , 1987, 16, 79-90.	0.4	26
26	Revisiting the multi-step method: Enhanced error separation and reduced amount of measurements. <i>CIRP Annals - Manufacturing Technology</i> , 2015, 64, 491-494.	1.7	23
27	Analysis of tin dioxide coatings by multiple angle of incidence ellipsometry. <i>Thin Solid Films</i> , 1989, 169, 1-16.	0.8	22
28	A novel technique for calibration of polygon angles with non-integer subdivision of indexing table. <i>Precision Engineering</i> , 2002, 26, 412-424.	1.8	22
29	Calibration of Displacement Laser Interferometer Systems for Industrial Metrology. <i>Sensors</i> , 2019, 19, 4100.	2.1	22
30	International comparisons of He-Ne lasers stabilized with $^{127}\text{I}_2$ at $\lambda = 633 \text{ nm}$ (July 1993 to September 1995). Part IV: Comparison of Western European lasers at $\lambda = 633 \text{ nm}$. <i>Metrologia</i> , 1999, 36, 199-206.	0.6	21
31	Achieving traceability and sub-nanometer uncertainty using interferometric techniques. <i>Measurement Science and Technology</i> , 2008, 19, 084002.	1.4	21
32	Virtual CMM using Monte Carlo methods based on frequency content of the error signal. , 2001, , .		20
33	Bandwidth characteristics and comparisons of surface texture measuring instruments. <i>Measurement Science and Technology</i> , 2010, 21, 079801.	1.4	19
34	International comparison of depth-setting standards. <i>Metrologia</i> , 1997, 34, 161-167.	0.6	18
35	Two-dimensional detection of subsurface damage in silicon wafers with polarized laser scattering. <i>Journal of Materials Processing Technology</i> , 2020, 284, 116746.	3.1	18
36	Scanning wafer thickness and flatness interferometer. , 2004, 5252, 334.		17

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37	Development of a double sided stitching interferometer for wafer characterization. CIRP Annals - Manufacturing Technology, 2006, 55, 555-558.	1.7	16
38	Hybrid dual laser processing for improved quality of inclined up-facing surfaces in laser powder bed fusion of metals. Journal of Materials Processing Technology, 2021, 298, 117263.	3.1	16
39	Uncertainty estimation by the concept of virtual instruments. , 2001, , .		15
40	Digital Twin of an Optical Measurement System. Sensors, 2021, 21, 6638.	2.1	15
41	On-machine chromatic confocal measurement for micro-EDM drilling and milling. Precision Engineering, 2022, 76, 110-123.	1.8	15
42	The Calibration of Displacement Sensors. Sensors, 2020, 20, 584.	2.1	14
43	Improving a commercially available heterodyne laser interferometer to sub-nm uncertainty. , 2003, , .		13
44	Validation of a single fibre-fed heterodyne laser interferometer with nanometre uncertainty. Precision Engineering, 2005, 29, 229-236.	1.8	10
45	Task specific uncertainty estimation in dimensional metrology. International Journal of Precision Technology, 2011, 2, 226.	0.2	10
46	<title>Long gauge block measurements based on a Twyman-Green interferometer and three stabilized lasers</title>. , 1998, 3477, 25.		9
47	The Utrecht accelerator facility for precision dating with radionuclides. Nuclear Instruments & Methods in Physics Research B, 1984, 5, 150-154.	0.6	8
48	Laser Polarization State Measurement in Heterodyne Interferometry. CIRP Annals - Manufacturing Technology, 2003, 52, 439-442.	1.7	8
49	Sphericity Measurement Using Stitching Interferometry. Key Engineering Materials, 0, 523-524, 883-888.	0.4	8
50	International comparison of noise in areal surface topography measurements. Surface Topography: Metrology and Properties, 2021, 9, 025015.	0.9	8
51	Straightness, flatness and cylindricity characterization using discrete Legendre polynomials. CIRP Annals - Manufacturing Technology, 2020, 69, 457-460.	1.7	8
52	Texture of inclined up-facing surfaces in laser powder bed fusion of metals. Additive Manufacturing, 2021, 42, 101970.	1.7	7
53	Dynamic probe calibration up to 10 kHz using laser interferometry. Measurement: Journal of the International Measurement Confederation, 1997, 21, 107-111.	2.5	6
54	CALCULATION OF MEASUREMENT UNCERTAINTY FOR MULTI-DIMENSIONAL MACHINES, USING THE METHOD OF SURROGATE DATA. , 2001, , .		6

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55	Uncertainty estimation of 2.5-D roughness parameters obtained by mechanical probing. International Journal of Precision Technology, 2013, 3, 403.	0.2	6
56	Depolarization of surface scattering in polarized laser scattering detection for machined silicon wafers. Precision Engineering, 2022, 73, 203-213.	1.8	6
57	Fiber characterization for application in heterodyne laser interferometry with nanometer uncertainty, part I: polarization state measurements. Optical Engineering, 2005, 44, 025002.	0.5	5
58	Surface profile and topography filtering by Legendre polynomials. Surface Topography: Metrology and Properties, 2021, 9, 015017.	0.9	5
59	Uncertainty evaluation and reduction in three-probe roundness profile measurement based on the system transfer function. Precision Engineering, 2021, 68, 139-157.	1.8	4
60	3D total variation denoising in X-CT imaging applied to pore extraction in additively manufactured parts. Measurement Science and Technology, 2022, 33, 045602.	1.4	4
61	<title>Ball diameter measuring instrument in a gauge block interferometer</title>. , 1998, 3477, 101.		3
62	Novel design of a one-dimensional measurement probe. , 2001, , .		3
63	Advanced Optical Incremental Sensors. , 2018, , 245-290.		3
64	International comparison of flatness deviation in areal surface topography measurements. CIRP Annals - Manufacturing Technology, 2022, 71, 453-456.	1.7	3
65	Relations between the optical, electrical, and structural properties of fluorine-doped tin dioxide coatings. , 1990, , .		2
66	Method for approximate noise elimination in form and roughness measurements. , 2003, , .		2
67	Accurate roughness measurements by dynamic calibration, VFM-uncertainty calculations and a special calibration specimen. Journal of Physics: Conference Series, 2005, 13, 232-235.	0.3	2
68	Fiber characterization for application in heterodyne laser interferometry, part II: modeling and analysis. Optical Engineering, 2005, 44, 025003.	0.5	2
69	Surface Texture Metrological Characteristics. , 2018, , 1-5.		2
70	NOISE CORRECTION FOR SURFACE MEASUREMENTS. , 2004, , .		2
71	Calibration of nanosensors with direct traceability to the meter. , 2001, , .		1
72	The detection of cyclic nonlinearities in a ZMI2000 heterodyne interferometer. , 2005, 5879, 205.		1

#	ARTICLE	IF	CITATIONS
73	Description and validation of a circular padding method for linear roughness measurements of short data lengths. <i>MethodsX</i> , 2020, 7, 101122.	0.7	1
74	Flatness. , 2016, , 1-6.		1
75	Flatness. , 2014, , 1-5.		1
76	Measurement Uncertainty. , 2014, , 852-857.		1
77	Investigations On Fluorine-Doped Tin Dioxide Films. <i>Proceedings of SPIE</i> , 1986, 0653, 137.	0.8	0
78	Accurate roughness measurements by laser interferometer calibration, VFM-uncertainty calculations and noise reduction. , 2005, 5879, 170.		0
79	Length Traceability Using Interferometry. , 2014, , 63-93.		0
80	Metrology: A New Open Access Journal with a Broad Scope and an Exciting Mission. <i>Metrology</i> , 2021, 1, 74-75.	0.9	0
81	Roughness. , 2014, , 1080-1082.		0
82	Reflectivity. , 2014, , 1042-1044.		0
83	Ellipsometry. , 2014, , 453-458.		0
84	Measurement Uncertainty. , 2016, , 1-5.		0
85	Stylus tip radius and wear estimation using the Rsk or the Rp and Rv parameter of a sine wave (Type C1) standard. <i>Surface Topography: Metrology and Properties</i> , 2022, 10, 015025.	0.9	0